

What is claimed is:

1. An enclosure for a probe station chuck, said probe station chuck including a device supporting surface and a thermal device arranged to modify a temperature of said device supporting surface, said enclosure comprising a conductive wall including an inner surface, said inner surface defining a chamber substantially enclosing said device supporting surface and having a portion separating said device supporting surface from said thermal device.
2. The enclosure of claim 1 further comprising an electrically conductive connection of said conductive wall to an instrument.
3. The enclosure of claim 2 further comprising an electrically conductive connection of said instrument to a ground.
4. The enclosure of claim 1 further comprising:
  - (a) an electrically conductive connection of said conductive wall to an instrument; and
  - (b) a switch having a first terminal selectively connectable to a second terminal, said second terminal being conductively connected to said conductive wall and said first terminal being conductively connected to a ground.
5. The enclosure of claim 4 further comprising an electrically conductive connection of said instrument to a ground.
6. The enclosure of claim 1 wherein said conductive wall further comprises a portion separating said device supporting surface from an electrical conductor arranged to conduct electrical energy from a controller to said thermal device.

7. The enclosure of claim 6 further comprising an electrically conductive connection of said conductive wall to an instrument.
- 5 8. The enclosure of claim 7 further comprising an electrically conductive connection of said instrument to a ground.
9. The enclosure of claim 6 further comprising:
- (a) an electrically conductive connection of said conductive wall to an instrument; and
  - 10 (b) a switch having a first terminal selectively connectable to a second terminal, said second terminal being conductively connected to said conductive wall and said first terminal being conductively connected to a ground.
- 15 10. The enclosure of claim 9 further comprising an electrically conductive connection of said instrument to a ground.
11. An enclosure for a probe station chuck, said probe station chuck including a device supporting surface and a thermal device arranged to modify a
- 20 temperature of said device supporting surface, said enclosure comprising a conductive wall including
- (a) an inner surface, said inner surface defining a chamber substantially enclosing said device supporting surface and having a portion separating said device supporting surface from said thermal
  - 25 device; and
  - (b) an outer surface, said outer surface including a portion substantially encircling a portion of said thermal device.

12. The enclosure of claim 11 further comprising an electrically conductive connection of said conductive wall to an instrument.
- 5 13. The enclosure of claim 12 further comprising an electrically conductive connection of said instrument to a ground.
14. The enclosure of claim 11 further comprising:
- 10 (a) an electrically conductive connection of said conductive wall to an instrument; and
- (b) a switch having a first terminal selectively connectable to a second terminal, said second terminal being conductively connected to said conductive wall and said first terminal being conductively connected to a ground.
- 15 15. The enclosure of claim 14 further comprising an electrically conductive connection of said instrument to a ground.
16. The enclosure of claim 11 wherein said outer surface includes another portion substantially encircling a portion of an electrical conductor arranged to conduct electrical energy from a controller to said thermal device.
- 20 17. The enclosure of claim 16 further comprising an electrically conductive connection of said conductive wall to an instrument.
- 25 18. The enclosure of claim 17 further comprising an electrically conductive connection of said instrument to a ground.

19. The enclosure of claim 16 further comprising:

(a) an electrically conductive connection of said conductive wall to an instrument; and

5 (b) a switch having a first terminal selectively connectable to a second terminal, said second terminal being conductively connected to said conductive wall and said first terminal being conductively connected to a ground.

20. The enclosure of claim 19 further comprising an electrically conductive  
10 connection of said instrument to a ground.

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